

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Mok, et al.

Serial No.: 09/785,815

Confirmation No.: 4127

Filed: February 16, 2001

For: INTEGRATED SEMICONDUCTOR
SUBSTRATE BEVEL CLEANING
APPARATUS AND METHOD

Group Art Unit: 1763

Examiner: Sylvia MacArthur

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April 7, 2004
Date

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Signature

**SUPPLEMENTAL RESPONSE TO
FINAL OFFICE ACTION DATED JANUARY 7, 2004**

In response to the Final Office Action dated January 7, 2004, having a shortened statutory period for response set to expire on April 7, 2004, please enter this supplemental response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/2601.P11/NAN, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Applicants Remarks** begin on page 7 of this paper.

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DATE: April 7, 2004
FILE NO: AMAT/2601.P11/CMP/ECP/RKK
TO: Examiner Sylvia MacArthur
FAX NO: 703/872-9306
PHONE NO: 571/272-1438
COMPANY: USPTO
FROM: Marie Henderson
Assistant to Keith M. Tackett
PAGE(S) with cover: 9
ORIGINAL TO FOLLOW? ☐ YES ☒ NO

SUPPLEMENTAL RESPONSE TO FINAL OFFICE ACTION DATED JANUARY 7, 2004

TITLE: Integrated Semiconductor Substrate Bevel Cleaning
Apparatus And Method
U.S. SERIAL NO.: 09/785,815
FILING DATE: February 16, 2001
INVENTOR: Mok, et al.
EXAMINER: Sylvia MacArthur
GROUP ART UNIT: 1763
CONFIRMATION NO.: 4127

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